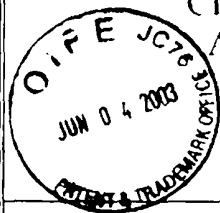


# INFORMATION DISCLOSURE CITATION IN AN APPLICATION



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 ATTY DOCKET NO  
49959-220

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09/986,137

 APPLICANT  
Gilad ALMOGY, et al.

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3662

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EXAMINER'S INITIALS	CITE NO	Include a link of the author in CAPITAL LETTERS; title of the article (when appropriate); title of the item; book, magazine, journal, serial, symposium, catalog, etc.; date, page(s), volume/issue number(s); publisher, city and country, where published
<i>[Handwritten initials]</i>		Partial International Search Report dated 5/5/03

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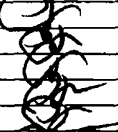
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